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CONFIRMATION NO. 4998

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APPLICANTS Hitoshi Kato, Tokyo, JAPAN; Koichi Orito, Tokyo, JAPAN; Hiroyuki Kikuchi, Tokyo, JAPAN; Shingo Maku, Tokyo, JAPAN;					
** CONTINUING DATA ***** This application is a 371 of PCT/JP04/00370 01/19/2004 <i>MDW 9/9/05</i>					
** FOREIGN APPLICATIONS ***** JAPAN 2003-016659 06/24/2003 <i>MDA 9/9/05</i>					
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Verified and <i>Monica D. Palmer MDH</i> Acknowledged <i>Examiner's Signature</i> <i>Initials</i>		STATE OR COUNTRY JAPAN	SHEETS DRAWING 4	TOTAL CLAIMS 15	INDEPENDENT CLAIMS 2
ADDRESS 22850					
TITLE Method of cvd for forming silicon nitride film on substrate					
FILING FEE RECEIVED 900	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		